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	Filing Date		2005-05-25	
	First Named Inventor	Migaku TAKAHASHI et al.		
	Art Unit	1792		
	Examiner Name	Alain L. BASHORE		
	Attorney Docket Number	YIPO:002		

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1	Migaku TAKAHASHI et al., "The Ultra Clean Sputtering Process and High Density Magnetic Recording Media", IEEE Transactions on Magnetics, September 1997, pgs. 2938-2943, Volume 33, Number 5, IEEE	<input type="checkbox"/>
2	E.N. ABARRA et al., "Longitudinal magnetic recording media with thermal stabilization layers", Applied Physics Letters, October 16, 2000, pgs. 2581-2583, Volume 77, Number 16, American Institute of Physics	<input type="checkbox"/>
3	J.C.S. KOOLS, et al., "Effect of finite magnetic film thickness on Néel coupling in spin valves", Journal of Applied Physics, April 15, 1999, pgs. 4466-4468, Volume 85, Number 8, American Institute of Physics	<input type="checkbox"/>

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